

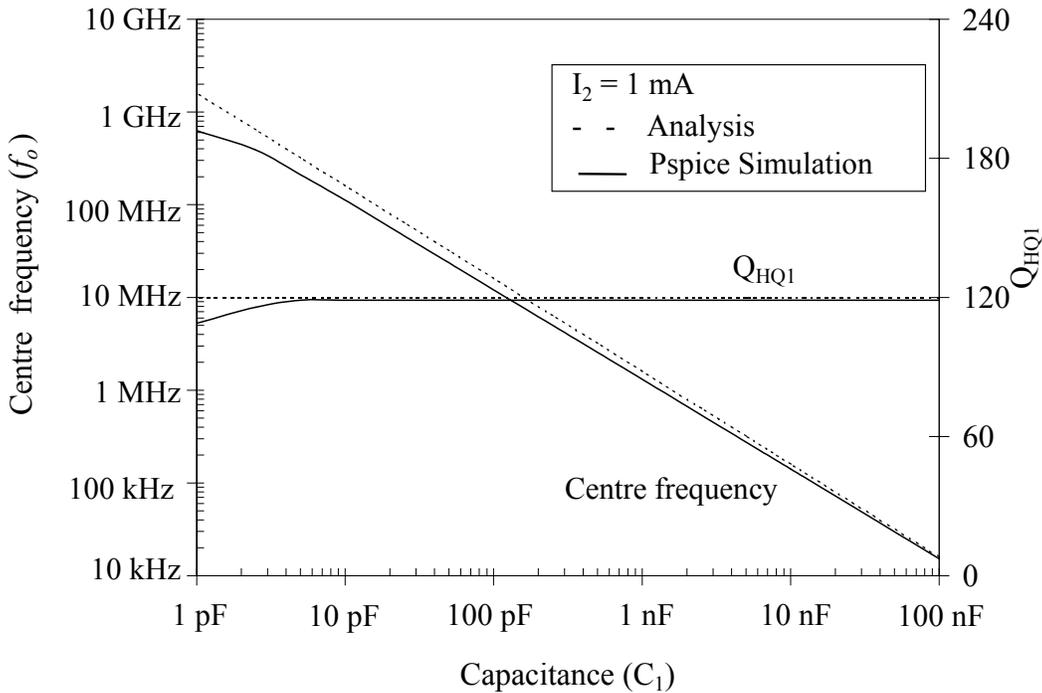
**Figure 4.19** Preliminary interpolation of the power consumption ( $P_{C2}$ ) and the dynamic range (DR2) of Technique 2 at 1%  $IM_3$  versus  $C_1$  at  $f_0 = 10.7$  MHz and  $Q_{HQ2} = 223$

#### 4.9 High-Frequency Performance

High-frequency performance of the circuit will be limited by the transition frequency ( $f_T$ ) of the transistor. Equation (3.9) suggests that a higher, more useful, center frequency can be expected using a smaller value of capacitor  $C_1$  (e.g. using stray capacitances), a higher value of  $I_2$  and a higher  $f_T$  (e.g. in the region of several GHz) of better transistors. For Techniques 1 and 2 described in Chapter 3, all transistors in Figures 3.2 and 3.3 are alternatively modeled by a better transistor BFR90A with higher  $f_T$  at 5 GHz (RF Transistor Data, Vishay Semiconductor GmbH, 1999),  $\beta = 120$  and the bias currents  $I_1 = I_2 = 1$  mA.

### 4.9.1 High-Frequency Simulation of Technique 1

Figure 4.20 shows high-frequency simulation of Technique 1 shown in Figure 3.2 through the analysis and the PSPICE simulations in terms of the center frequency  $f_{o1}$  and the quality factor  $Q_{HQ1}$  versus capacitance  $C_1$ . In Technique 1,  $Q_{HQ1}$  is maintained relatively high and the upper frequency is limited at approximately 600 MHz at  $C_1 = 1$  pF.

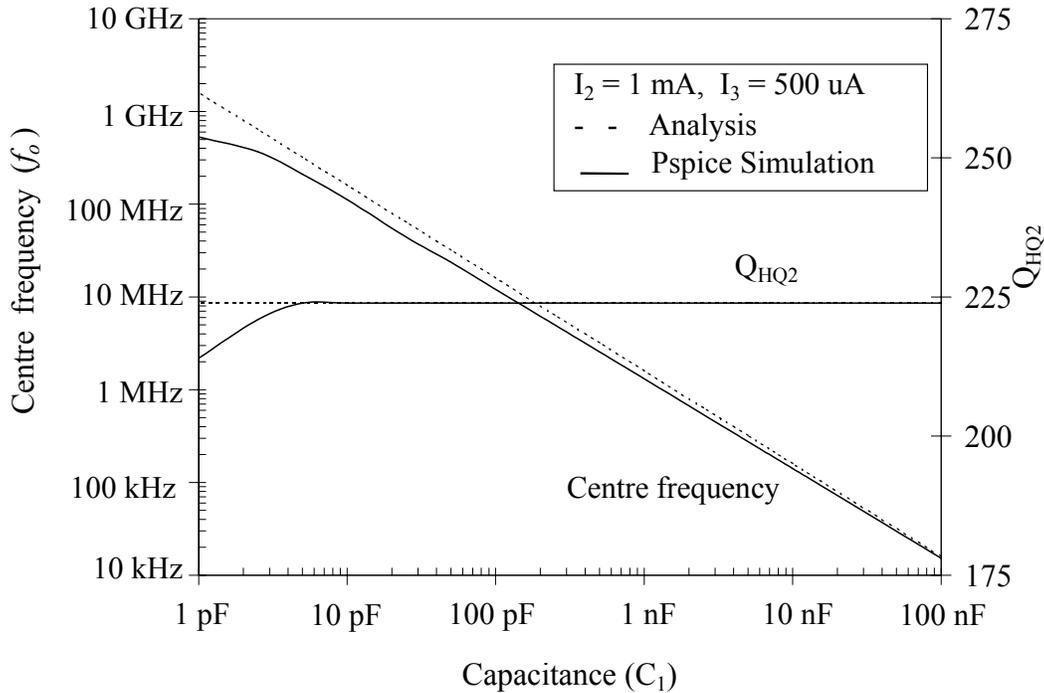


**Figure 4.20** An example of the center frequencies  $f_o$  and the quality factor  $Q_{HQ1}$  versus capacitance  $C_1$  of Technique 1 shown in Figure 3.2.

### 4.9.2 High-Frequency Simulation of Technique 2

Similarly, Figure 4.21 illustrates high-frequency simulation of Technique 2 shown in Figure 3.3 through the analysis and the PSPICE simulation in terms of the center frequency  $f_{o2}$  and the quality factor  $Q_{HQ2}$  versus capacitance  $C_1$ . Both bias currents  $I_1$  and  $I_2$  are fixed at

1 mA and  $I_3 = 0.5$  mA. In Technique 2,  $Q_{HQ2}$  is maintained relatively high and the upper frequency is limited at approximately 500 MHz at  $C_1 = 1$  pF.



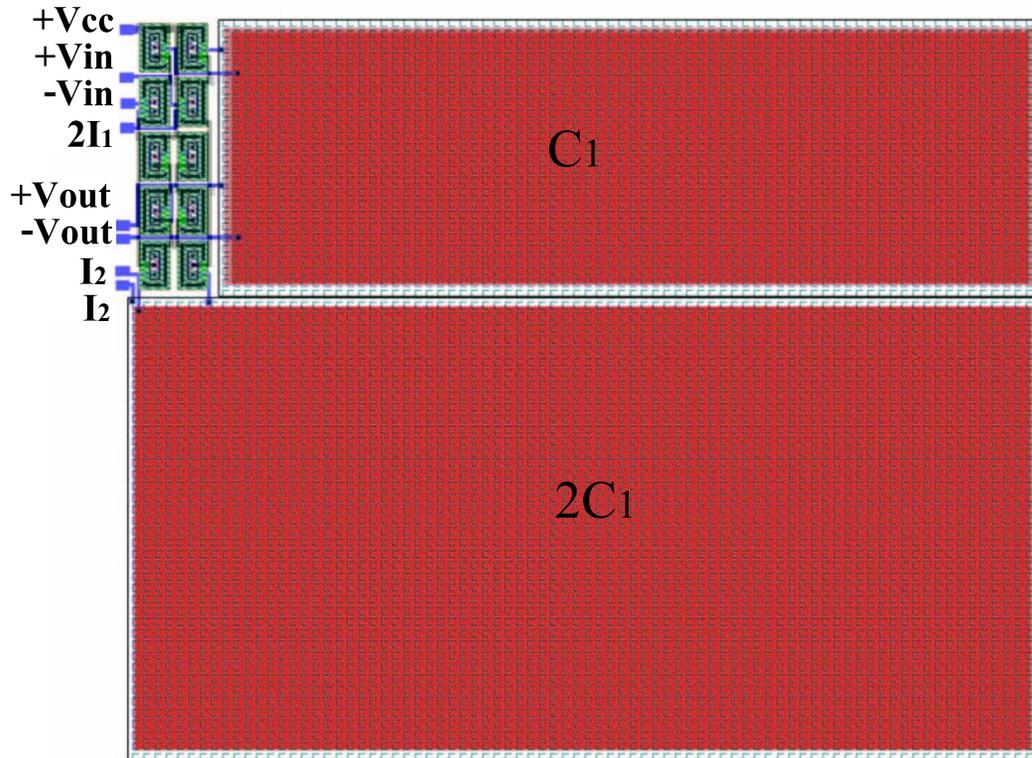
**Figure 4.21** An example of the center frequencies  $f_0$  and the quality factor  $Q_{HQ2}$  versus capacitance  $C_1$  of Technique 2 shown in Figure 3.3.

#### 4.10 Physical Layout Simulations

Figure 4.22(a) shows a physical layout of the circuit in Technique 1 which correspond to Figure 3.2. Figure 4.22(b) shows an exploded version of the layout of Technique 1 excluding capacitors  $C_1$  and  $2C_1$ . Figure 4.23(a) shows a physical layout of the circuit in Technique 2 which correspond to Figure 3.3. Figure 4.23(b) shows an exploded version of the layout of Technique 2 excluding capacitors  $C_1$  and  $2C_1$ . As a particular example, the layouts are modeled by 1.2 $\mu$ m N-well Technology of ORBIT Semiconductor. As shown in Figure 4.22 and 4.23, the circuit layout consists of NPN transistors, capacitors and resistors. A NPN transistor is formed by a P\_BASE, N\_WELL, N\_SELECT, METAL1 and ACTIVE\_AREA.

The P\_BASE layer is an active area. The base contact is enclosed in N\_SELECT. The emitter is an N\_SELECT region. The collector is the entire P\_BASE sitting in an N\_WELL. A contact hole is modeled by a CONTACT, a METAL1 and an ACTIVE\_AREA. The area of a NPN transistor is approximately  $0.0385 \text{ mm(Width)} \times 0.0605 \text{ mm(Length)} = 2.32925 \times 10^{-3} \text{ mm}^2$ . The  $\beta$  parameter obtained from measurements is 128.

A capacitor is formed by POLY and POLY\_CAP1. The POLY\_CAP1 surrounds the POLY everywhere; the area of the capacitor is the area of the POLY. POLY is physically on top of POLY\_CAP1, so that contact to the POLY\_CAP1 must be made in the region where it extends beyond the POLY. The area of the POLY of  $1.9773 \times 10^{-3} \text{ mm}^2$  results in the capacitor of 1 pF and the large area. A resistor is formed by POLY\_R and METAL1. The area of the METAL1 of  $69.75 \times 10^{-6} \text{ mm}^2$  results in the resistor of 50  $\Omega$ . As shown in Figure 4.22 and 4.23, the area of the circuit layouts are approximately  $1.12 \text{ mm(Width)} \times 0.90 \text{ mm(Length)} = 1.008 \text{ mm}^2$  and  $0.88 \text{ mm(Width)} \times 1.13 \text{ mm(Length)} = 0.994 \text{ mm}^2$ , respectively. The performance of the circuit layout has been simulated through parasitic extractions.



**Figure 4.22 (a)** The layout of Technique 1 shown in Figure 3.2 where  $C_l=150\text{ pF}$